OILFREE SCROLL VACUUM PUMPS

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DRY SCROLL VACUUM PUMP





Air Flush

Air Flush

Purpose of Air Flush Pumping of humid gas by vacuum pump can cause condensed moisture to remain in pump. This remaining moisture can cause failure to ultimate pressure or pump. Air Flush operation is necessary to remove remaining moisture inside. Air Flush operation also recovers ultimate pressure.

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The model name of ISP-1000 is ISP-1000-TVA/THA, ISP-50 is change to ISP-50-SV1; single phase 100V, ISP-50-SV2; single phase 200V

Trade name			Oil-free Scroll Vacuum Pump					
Model			ISP-50	ISP-90	ISP-250C	ISP-500C	ISP-1000E	
	L/min		50	90	250	500	1000	
Pumping speed (50 Hz)	m³/h		3,0	5,4	15,0	30,0	60,0	
(5011-)	≦ Pa		20	5	1,6 1		1	
Ultimate pressure (50Hz)	≦ mbar		2,0 ×10 ⁻¹	5,0 ×10 ⁻²	1,6 ×10 ⁻² 1,0 ×10 ⁻²		1,0 ×10 ⁻²	
Motor power	kW	-	0,1	0,15	0,4 0,6		1,4	
Voltage	V	Singie phase	AC100V, AC200V, AC 230V	100,115,200,230 (with thermal protector)			-	
		Three phase	-	- 200,208,230,380,450,460)	
Noise level	dB((A)	48 (at air flush 57)	52 (at air flush 57)	58 (at air flush 66) 60 (at air flush 68)		67 (at air flush 74)	
Weight	Kg	Singie phase	12	14	25	44	-	
		Three phase	-	-	23	38	56	
Leak tightness	Pa ∙ m/s		≦ 1 x 10 ⁻⁷		≤ 1 x 10 ⁻⁵			
Water Vapor Capacity	g/day		3 (at air flush)	5 (at air flush)				
Air flush	L/min		4	9	10			
Inlet connection	NW		25			40		
Outlet connection	NW			25	40			
Cooling system			air-cooled					
Ambient temperature	°C			10~40				

Ultimate pressure is measured as total pressure. Noise is measured in an anechoic room.



Synchrotron Facility Evacuation units for beamlines in Synchrotron and Accelerator Facilities



High Vacuum Pumping System

Roughing pump for Turbo Molecular Pump and Mechanical Booster Pump



- Sputtering equipment, Vacuum deposition equipment, lon plating equipment
- Gas recovery devices
- Vacuum equipment
- Leak detectors
- Device handling system

- Surface modification, Electron beam process
- Vacuum furnace, Heat treatment furnace
- Laboratory use
- Vacuum packaging machine
- Others



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DVSL-100C



DVSL-500E/501E



DVSL-501E-HC



Introducing the HC model with increased durability in DVSL series! It lasts three-times longer than the standard model, thanks to the specialized finishing which is applied to the sliding surface. It is highly recommended to end-users who process water vapor frequently.

Product dimensions are the same as the DVSL-501C.

• Numbers and values are comparison to our current products and reference only. Results are varied depending upon application and condition of use.

DVSL-1002E







DRY SCROLL VACUUM PUMP

Excellence in continuous operation between atmosphere and vacuum and in displacing water vapor.



Air Flush

Purpose of Air Flush

Pumping of humid gas by vacuum pump can cause condensed moisture to remain in pump.

This remaining moisture can cause failure to ultimate pressure or pump.

Air Flush operation is necessary to pump remaining moisture inside the pump.

Air Flush operation dose not only pump remaining moisture but also recovers ultimate pressure.

Specifications

Trade n	ame)	Oil-free Scroll Vacuum Pump					
Mod	el		DVSL-100C	DVSL-500E	DVSL-501E	DVSL-1002E		
Pumping speed	L/min		100	430	430	845		
(50 Hz)	m³/h		6,0	25,8	25,8	50,7		
Ultimate pressure	≤ Pa		50	30	100	30		
(50Hz)	≤ mbar		5,0 ×10 ⁻¹	3,0 ×10 ⁻¹	1,0 ×10 ⁻⁰	3,0 ×10 ⁻¹		
Motor power	kW		0,3	0,9	0,9	2,4		
Valtara	v	Singie phase	100,115,200,230	-	-	-		
Voltage	v	Three-phase	-	200,208,230,380,400,415,460		200,220		
Noise level	dB(A)		\leq 62 (at air flush 65)	\leq 64 (at air flush 69)		\leq 69 (at air flush 74)		
Weight	K.	Singie phase	15	-		-		
weight	Kg	Three-phase	-	36		118		
Water vapor		g/day	100 (at air flush)	250 (at air flush)		500 (at air flush)		
Air flush		L/min	5 (at air flush)	10 (at air flush)		20 (at air flush)		
Inlet connection		NW	NW25 (with Rc 3/8)	NW25 (with Rc 1/2)		Rc 1		
Outlet connection	NW		NW16 (with Exhaust valve)	NW25 (with Exhaust valve)				
Cooling system			air-cooled					
Ambient temperature	°C		5~40					
Back-up material			Fluorine rubber	Silicon rubber	Fluorine rubber	Silicon rubber		

Pumping speed



• Pumping speed of DVSL-501C-HC is the same as the DVSL-501C.

VACUUM EQUIPMENT APPLICATIONS

Vacuum equipment of Anest Iwata are utilized in various applications.





ANEST IWATA GLOBAL NETWORK





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